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## U.S. PATENT DOCUMENTS

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	AA						
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## FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
PN	AF	WO 02/27063 A2	04/04/02	WIPO				
	AG							

## OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

PN	AH		*Atomic Layer Deposition of SiO <sub>2</sub> Using Catalyzed And Uncatalyzed Self-Limiting Surface Reactions*, J.W. Klaus et al; Surface Review					
			and Letters, Vol. 6, Nos. 3 & 4 (1999) pp. 435-448					
	AI		Self-limiting chemical vapor deposition of an ultra-thin silicon oxide film using tri-(tert-butoxy)silanol*, K.A., Miller et al;					
			Thin Solid Films 397 (2001); pp. 78-82)					
	AJ		*Reactive Deposition of Metal Thin Films within Porous Supports from Supercritical Fluids*, Neil E. Fernandes et al.; Chem Mater. 2001;					
			13, pp. 2023-2031					
	AK		*Supercritical CO <sub>2</sub> Processing for Submicron Imagine of Fluoropolymers*, Narayan Sundararajan et al; Chem. Mater. 2000; 12;					
			pg. 41-48					
	AL		*Supercritical carbon dioxide assisted aerosolization for thin film deposition, fine powder generation, and drug delivery*;					
			C.V. Xu et al.; P.T. Anastas; T.C. Williamson, Green Chemistry, 5, pp. 313-335; Oxford University Press, Oxford 1998					
PN	AM		*Supercritical Fluid Transport-Chemical Deposition of Films*, Brian N. Hansen et al.; Chem Mater. 1992; 4; pp. 749-752					

EXAMINER

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